

In The Claims:

Please amend claims 1 and 5 and add new claims 12-17 as follows:

1. (Amended) A polishing apparatus for polishing a substrate, comprising:

a turntable having a polishing surface;

a substrate holder for holding a substrate and bringing the substrate into contact under pressure with said polishing surface;

a dresser including a dresser tool adapted to be brought into contact under a pressure with said polishing surface to dress or condition said polishing surface; and

a pressure device connected to said dresser for moving said dresser between a raised position where said dresser is spaced away from said polishing surface and a dressing position where said dresser rests on said polishing surface such that said dresser tool is in contact with said polishing surface under a pressure exerted by the weight of said dresser itself, said pressure device including a member for applying an upward force to said dresser to decrease the pressure during a dressing operation.

5. (Amended) A polishing apparatus comprising:

a turntable having a polishing surface;

a substrate holder for holding a substrate and bringing the substrate into contact under pressure with said polishing surface;

a dresser tool adapted to be brought into contact under pressure with said polishing surface to dress or condition said polishing surface; and

a dresser tool holding device for holding said dresser tool and moving said dresser tool between a raised position where said dresser tool is spaced away from said polishing surface and a dressing position where said dresser tool rests on said polishing surface with a pressure being exerted by said dresser tool on said polishing surface by only the weight of said dresser tool itself.

12. (New) A polishing apparatus for polishing a substrate comprising a polishing surface, said polishing apparatus comprising:

a substrate holder for holding a substrate and bringing the substrate into contact with the polishing surface; and

a dresser for dressing the polishing surface, said dresser comprising a dresser tool adapted to be brought into contact with the polishing surface, and a dresser shaft for elevating said dresser tool to a position where said dresser tool is spaced away from the polishing surface and a lowered position where said dresser tool is in contact with the polishing surface,

wherein said dresser tool and said dresser shaft are arranged so as to be movable toward and away from each other during a dressing operation.

13. (New) A polishing apparatus according to claim 12, wherein said dresser shaft is connected to said dresser tool by a torque transmission pin for transmitting rotational torque from said dresser shaft to said dresser tool.

14. (New) A polishing apparatus according to claim 13, wherein said dresser shaft comprises a flange, and said torque transmission pin is extended through said flange.

15. (New) A polishing apparatus according to claim 12, further comprising a bearing for supporting said dresser tool relative to said dresser shaft in a manner enabling said dresser tool to be inclined relative to said dresser shaft.

16. (New) A polishing apparatus according to claim 15, wherein said bearing comprises a ball bearing.

17. (New) A polishing apparatus according to claim 15, wherein said bearing comprises a roller bearing.